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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Armin KUEBELBECK ET AL.

Examiner: Empie, Nathan

Serial No.: 10/526,497

Group Art Unit: **1709**

Filed: March 4, 2005

Title: ETCHING PASTES FOR SILICON SURFACES AND LAYERS

Amendment and Reply to Office Action

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SIR:

In response to the Office Action mailed 27 April 2007, please amend the application and consider the remarks that follow:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.